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WAFER MANAGEMENT SYSTEM AND METHODS FOR MANAGING WAFERSAbstract of the Disclosure

- 5 A wafer management system has a first stationary wafer storage system (100) with a first buffer (110) for storing a plurality of wafers in slots, a first load-and-unload station (115) for transferring the wafers between the first buffer (110) and intra-bay pods (120, 130) assigned to a first bay (160), and a second load-and-unload station (184) for transferring wafers between the first buffer (110) and further pods (520, 530). The storage system (100) and the bay (160) form a single unit. Multiple units are linked together by tracks (500).
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